

L Number	Hits	Search Text	DB	Time stamp
1	179	(projection with (lens\$2 or system\$1)) and (gas\$2 near3 composition)	USPAT; US-PGPUB	2003/09/29 10:03
2	50	(projection with (lens\$2 or system\$1)) and ((gas\$2 near3 composition) same (chang\$3 or adjust\$3))	USPAT; US-PGPUB	2003/09/29 11:22
61	2928	(projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:24
62	698	((projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))) and ((light or lamp) same nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:23
63	589	((projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:24
64	2928	(projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 13:36
65	589	((projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 13:37
66	294	((projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm)) and (projection near3 exposure)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:33
67	294	((projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm)) and (projection near3 exposure)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:29
68	175	((projection with (lens\$2 or system\$1)) and (((gas\$2 near3 composition) or pressure) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm)) and (projection near3 exposure)) and (lithograph\$3 or microlithograph\$3 or (micro near2 lithograph\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:33
69	359	(projection with (lens\$2 or system\$1)) and ((gas\$2 near3 (composition or pressure)) same (chang\$3 or adjust\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:33
70	537	(projection with (lens\$2 or system\$1)) and ((gas\$2 with (composition or pressure)) same (chang\$3 or adjust\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:33
71	199	((projection with (lens\$2 or system\$1)) and ((gas\$2 with (composition or pressure)) same (chang\$3 or adjust\$3))) and (projection near3 exposure)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:33
72	126	((projection with (lens\$2 or system\$1)) and ((gas\$2 with (composition or pressure)) same (chang\$3 or adjust\$3))) and (projection near3 exposure)) and (lithograph\$3 or microlithograph\$3 or (micro near2 lithograph\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 11:34

73	359	((projection with (lens\$2 or system\$1)) and ((gas\$2 near3 (composition or pressure)) same (chang\$3 or adjust\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 13:47
74	148	((projection with (lens\$2 or system\$1)) and ((gas\$2 near3 (composition or pressure)) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 13:37
75	148	((projection with (lens\$2 or system\$1)) and ((gas\$2 near3 (composition or pressure)) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm) and ((gas\$2 near3 (composition or pressure)) same (chang\$3 or adjust\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 13:47
76	119	((projection with (lens\$2 or system\$1)) and ((gas\$2 near3 (composition or pressure)) same (chang\$3 or adjust\$3))) and ((light or lamp) with nm) and ((gas\$2 near3 (composition or pressure)) with (chang\$3 or adjust\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/29 13:47